the result of impressively successful development since mag- recording industry.

mercial advances have been made. Media storage capacity has been dramatically raised from 5 to 10 Mbyte (megabytes) per disk platter in the early 1980s to 2 to 4 Gbyte (gigabytes) per disk platter in early 1998. (A decimal base is not used for numbers describing data stored. Arising from the computing usage of binary numbers, 1 Mbyte is the nearest power of 2 equivalent of 1 million, in other words, 1,048,576 bytes $\equiv 2^{20}$ bytes; and 1 Gbyte is the nearest binary equivalent of 10^9 , that is, 2^{30} , bytes, in other words, $1,073,741,824$ bytes.) In the same period, the price of a disk platter has also fallen by more than a factor of 100. Despite these successes, progress in raising the areal density (number of data bits per unit area) of recording media has not stopped or slowed down, and the total data storage capacity of disk drives is still increasing rapidly. It is predicted that an areal density of 20 Gbit/in.2 will be demonstrated, and that media above 10 Gbit/in.² should be available commercially by the turn of the century. (With respect to disk diameter and area, the units used in the United States are still the inch and square inch, respectively.)

The purpose of this article is to give an overview of magnetic recording media, especially of the thin-film media developed recently on rigid disks, since this is the dominant, continuing area of magnetic recording media research and commercial progress. We begin with a short look at the history of recording media, followed by detailed discussion of current media and reference to the future of these media.

Historical Perspective

The earliest magnetic recording medium was a wire made of stainless steel, containing nickel and chromium. The wire was annealed so that single-domain particles of the ferrite phase precipitated in an austenitic, nonmagnetic matrix (1). The resulting coercivity of this wire recording medium, that is, the applied magnetic field required to reduce the magnetization to zero, was only a few hundred oersteds. This type of medium served to establish the concept of magnetic recording. However, the medium was never commercialized for two practical reasons: the recording head could not reliably read all the previously recorded information, since the wires were easily twisted, and the read–write process was interrupted whenever the thin wires broke and needed to be "repaired" by knotting the broken ends together. To improve upon this type of magnetic recording medium and to avoid its mechanical problems, a spliceable tape coated with synthetic particles, including γ -Fe₂O₃, was developed in the early 1940s (2). The particles were aciculate (needle-shaped) and were held with their long axes parallel to a polymer tape backing. The particles were believed to be single domain and to undergo magnetization reversal by coherent rotation. Extensive research and development work since that time has led to the successful commercial applications of a wide variety of magnetic tape media.

The particulate-coating approach was extended to rigid **MAGNETIC STORAGE MEDIA** disk media in the 1950s with IBM's development of the first rigid magnetic recording medium—a 24 in. disk coated with Magnetic recording of data relies on the controlled creation γ -Fe₂O₃. As the technology evolved, in the late 1970s the sputand reliable detection of regions of differing magnetization in tering form of vacuum deposition became well established as a magnetic medium. Today's magnetic recording media are the method for applying the magnetic layer in the magnetic

netic recording media were invented and first demonstrated Sputtering is far superior to the earlier coating methods 70 years ago. The development has been particularly fast in for making films because it can create a much higher packing the last 15 to 20 years, during which many technical and com- density of the magnetic constituents, and this is a prerequisite for higher recording densities. The magnetic materials used in the vacuum deposition were mostly CoCr alloys (3,4), which easily provided media coercivities of about 300 Oe to 500 Oe—a large improvement from the 200 Oe to 300 Oe coercivities of γ -Fe₂O₃–coated particulate media. By the early 1980s, ternary CoCrX alloys (X being a metallic element), such as CoCrNi and CrCrTa, had evolved with substantially improved recording media characteristics (5). With the addition of Ni or Ta, the anisotropy of the alloys was greatly increased, resulting in higher coercivities and better recording performance. The ternary alloys CoCrTa have been so successful so that they have been widely used in the past 10 years, until they reached a coercivity limit at about 2500 Oe to 2700 Oe. Exceeding that limit has involved a large effort throughout academia and industry. By the early 1990s, Pt was found to be an excellent candidate for increasing the magnetocrystalline anisotropy by forming CoCrPt- and CoCrPtTa-based alloys (6,7,24) and so enhancing magnetic film coercivities. Since the crystalline anisotropy is a key intrinsic parameter for increasing the film coercivity, quater-
nary alloys have therefore emerged as the means to further of magnetic reading process. (b) Illustration
of magnetic reading process. development of high-recording-density media by breaking the ternary coercivity limit. Coercivities up to 4000 Oe have reliably been obtained for the CoCrTaPt alloy system (8). At the of H_x is at $x = 0$ and can be expressed as same time, other high-anisotropy alloys, such as CoSm- and FeSm-based alloys, have also been studied but their recording characteristics, both from academia and from industry, have been exceeded by the quaternary alloy CoCrPtTa. Develop-

Fundamentals of Magnetic Recording $H_x(0, d + \delta)$
 Megnetic recording is based on storing information in a magnetic given H_c as

Magnetic recording is based on storing information in a magnetic medium by controlled writing (creation) of regions with differing magnetization. Requirements for high-density longitudinal recording media include desirable bulk magnetic properties, appropriate magnetic domain structure, and stability of the magnetizations and the read-write process. In
this section we briefly review the writing and reading pro-
cesses and analyze their performance, which is correlated
culting a magnitude for H_g , $H_c = 2000$ Oe vith bulk magnetic properties and the spacing between the
head and the medium. The section concludes with a short dis-
cussion of thermal stability, which is also correlated with the
micromagnetic properties. The magnetic

Extract of the magnetic properties. The magnetic domain and medium
micromagnetic properties. The magnetic domain and medium
microstructure will be discussed in the later sections.
The writing process is illustrated in Fig

$$
H_x(x, y) = \frac{H_g}{\pi} \left(\arctan \frac{x + g/2}{y} - \arctan \frac{x - g/2}{y} \right) \tag{4}
$$

inside the head gap, and x and y are the coordinates at which one parameter a is needed to specify the transition character- H_x is to be calculated, as shown in Fig. 1(a). The peak value istics: a small value of *a* corresponds to a rapid transition,

$$
H_{x(\text{peak})} = H_x(0, y) = 2\frac{H_g}{\pi} \left(\arctan\frac{g/2}{y}\right) \tag{2}
$$

ment of underlayer and seed-layer technologies and optimiza-
tion of the manufacturing process has also assisted in ob-
taining dramatic improvements in the performance of media,
including the media signal-to-noise ratio H_c . Taking $x = 0$, $y = d + \delta$ (where d is the spacing between head and medium and δ is the medium layer thickness) and $H_x(0, d + \delta) = 2.5H_c$, one can calculate the required H_g for a

$$
H_{g} = \frac{2.5\pi H_{c}}{2\arctan\left(\frac{g}{2(d+\delta)}\right)}
$$
(3)

$$
M_x = \frac{2}{\pi} M_r \left(\arctan \frac{x}{a} \right) \tag{4}
$$

where M_r is the remanent magnetization of the medium and where *g* is the gap width of head, H_g is the magnetic field *a* is known as the transition parameter. It is notable that only

ten magnetic transition in the medium passes under the head effects (109,110). Using the thermal activation model, Shargap, the stray magnetic field from the medium will cause a rock pointed out that the measured coercivity H_c is timechange in magnetization in the head core and so will result dependent and can be expressed as in an induced output signal from the head coil. This signal is correlated with the head and medium parameters and the spacing between them. For an arctan magnetization transition, this output voltage can be expressed as follows (9,11,12):

$$
V(x', d) = -2\mu_0 \left(\frac{\eta n v w}{\pi g}\right) (M_r \delta)
$$

$$
\times \left(\arctan \frac{x' + g/2}{a + d} - \arctan \frac{x' - g/2}{a + d}\right)
$$
 (5)

of coil turns in a head, the velocity of the medium relative $\frac{1}{2}$ writing (small t). To satisfy the thermal stability requirement, respectively. We note that Eq. (5) has the same form as Eq. (1) and the output voltage $V(x', d)$ is proportional to $M_r \delta$. Taking $x' = 0$ in Eq. (5), the peak voltage V_{p-p} is

$$
V_{\mathbf{p}-\mathbf{p}} = 8\mu_0 \left(\frac{\eta \, nvw}{\pi g}\right) (M_{\mathbf{r}}\delta) \left(\arctan\frac{g/2}{a+d}\right) \tag{6}
$$

maximum amplitude level, is called PW_{50} and is given by

$$
PW_{50} = [g^2 + 4(a+d)(a+d+\delta)]^{1/2}
$$
 (7)

where a is the transition parameter introduced in Eq. (4) . The derivation of an expression for *a* has to take into account the details of the writing process. We shall not go into this process but simply give the result (89): holds, the medium will lose coercivity and become superpara-

$$
a = 2\sqrt{\frac{M_{\rm r}\delta(d + \delta/2)}{H_{\rm c}}}
$$
 (8)

The desirable bulk magnetic properties of media for high- In summary, high-density recording requires a high medensity recording can be understood by considering the pulse width of an output signal. A narrow pulse, that is, a small enough to give sufficient output signal, the most appropriate PW_{50} , will allow an increase in the linear recording density. way to reduce the transition *a* is by increasing coercivity H_c . Equation (7) suggests that small g , d , δ , and α favor a de-Equation (7) suggests that small g, d, δ , and a favor a de- However, one should notice the correlation between H_c and crease in the value of PW₅₀ and therefore an increase in the H_c in Eq. (3) and should choose a linear density. However, the values of g , d , and δ are limited by other considerations: the gap width *g* has to be large terial. The grain size has to be large enough to provide therenough to produce a sufficient field [see Eqs. (1) and (2)]; the mal stability, but as small as practical to increase the signalhead–medium spacing *d* has to be large enough to prevent to-noise ratio and reduce the transition width. It should also mechanical wear of both the head and medium, and so has a be pointed out that high anisotropy K_u favors the enhanceminimum value that is limited by the surface roughness of ment of both H_c and thermal stability.

the medium; and the medium thickness δ has to be great enough to provide sufficient signal [see Eqs. (5) and (6)]. To reduce δ and retain sufficient output signal, a large $M_{\rm r}$ of the medium is preferred. Therefore, an important approach to reducing PW_{50} is to shorten the transition parameter a , guided by Eq. (8), which indicates that this optimally requires de- $\emph{creasing }$ $\emph{M}_\text{r} \delta$ and increasing H_c .

Thermal stability is another important issue in high den-Figure 2. Arctangent form of magnetic transition. sity recording as the crystalline grain size is reduced to attain increased areal recording density. The grain size should be as small as practical to satisfy the needs for a narrow transition, and this favors high-density recording, as will be discussed in a high signal-to-noise ratio, and a smooth film surface. Howmore detail in connection with the reading process. ever, the grain size must be large enough to provide adequate The reading process is illustrated in Fig. 1(b). When a writ- thermal stability to guard against time-dependent magnetic

$$
H_{\rm c}(t) = H_{\rm o} \left\{ 1 - \left[\frac{k_{\rm B}T}{K_{\rm u}V} \ln(At) \right]^n \right\} \tag{9}
$$

where k_{B} , *T*, K_{u} , and *V* are the Boltzmann constant, absolute temperature, magnetic anisotropy, and grain volume, respec- (5) tively, A is a time-independent constant, and n varies from 1/2 to 2/3 depending on the orientation distribution of grain moments with respect to the field. Therefore, the coercivity where η , *n*, *v*, *w*, and *x*['] are the head efficiency, the number H_c that is relevant to long-term storage (large *t*) can be sig-
nificantly less than that which is relevant to high frequency

$$
\frac{K_{\rm u}V}{k_{\rm B}T} \ge 60 \text{ to } 80\tag{10}
$$

This formula indicates that a medium with high anisotropy K_u and large grain volume *V* will have enhanced thermal The width of the output pulse, measured at one-half of the stability. However, a large grain volume *V* will degrade the signal-to-noise ratio and transition width, both of which are undesirable.

 $Further analysis indicates that if the condition$

$$
\frac{K_{\rm u}V}{k_{\rm B}T} \le 25\tag{11}
$$

magnetic because the grains are too small to retain the orien $a = 2\sqrt{\frac{M_r \delta(d + \delta/2)}{H_c}}$ (8) tation of their magnetic moments, owing to thermal agitation.
This is the so-called superparamagnetic limit of recording media.

>). Since $M_{\rm r}\delta$ must be large H_g in Eq. (3) and should choose a high value of H_c that is within the saturation flux density limitation of the head ma-

The units used in describing magnetic recording media have
not been unique, although most in the field have adopted mks
units. Researchers and disk makers in the United States in
this field still use cgs units, partly bec used for magnetic recording media and their unit conversions.

Types of Magnetic Recording Media

Table 1. Parameters and Units Used in Magnetic Recording

Quantity	cgs	mks	Notes
Permeability of free space μ	1	$4\pi \times 10^{-7}$	
Intrinsic coercivity $H_{\rm c}$	Oe.	Oe.	
Remanent coercivity H_{cr}	Oе.	Oе.	$H_{cr} \geq H_c$
Moment per volume M	emu/cm ³	A/m	
Remanent magnetization M_r	emu/cm ³	A/m	
Product of remanent mo-	emu/cm ²	A/m ²	
ment and film thickness			
$M_{\cdot}\delta$			
Product of remanent mag-	G/cm^2		
netic field flux and film			
thickness $B_{r}\delta$			
Anisotropy constant K_u	ergs/cm ³	J/m ²	
Anisotropy field H_k	G	т	$1 T = 104 G$

Units Used for Magnetic Recording Media **ergons** are Co alloys, most commonly on a CoCr-alloy base

MAGNETIC RECORDING MEDIA ON RIGID DISKS

Magnetic recording media technology has rapidly evolved in The development of magnetic rigid recording disks has rapidly column that in the state and only and the find disks to find disks to find disks to find the find di

about \$5.00 per MB a decade ago. Progress in this technology continues and is expected to result in 10 Gbit/in.2 disks being commercially available at the turn of the century.

Studies of Magnetic Media on Rigid Disks

Magnetic recording media form one of the most successful research areas of transfer of research results into commercial application. Extensive studies of rigid media started in the early 1980s during the transition between electroplating and vacuum-sputtering technologies. Co, CoCr, CoCrNi alloys were the early materials studied in great detail (19–22). Fisher, Allan, and Pressesky proposed the CoCrTa magnetic alloy system (23), which lasted 10 years in commercial production until improvements in the performance of CoCrTa media became limited by coercivity limits of this alloy system. Lal and Eltoukhy (24) and other researchers (25) found that

the addition of Pt to CoCr or CoCrTa systems could dramatically increase film coercivity. With the quaternary alloy system, coercivity ranges as high as 4000 Oe have been achieved at higher Pt concentration (8).

Magnetic recording media can be classified into three categories according to the principles and schemes employed in the recording process. The first category comprises the longitudinal recording media, on which large numbers of studies have been reported around the world. Longitudinal recording is one of the most successful examples of academic research and commercial applications stimulating each other and of science leading directly to products. The second category is of the perpendicular recording media. Studies of these media have shown the high potential of perpendicular recording for ultrahigh area recording density. For practical reasons, this type of recording scheme is still not in use and there is no commercial product available. However, a large number of Figure 3. Illustration of the oblique evaporation process of making studies have been done, mostly in Japan, where the work **Figure 3.** Illustration of the oblique evaporation process of making originated and where there i tinuing academic discussion. The last category is of the longitudinal type of media that have an added ''keeper layer.'' Keeper layer media have also attracted considerable attention, which has resulted in quite a number of studies. The
rationale is that the resulting magnetic flux closure can in-
rationale is that the resulting magnetic flu

Techniques of Fabricating Recording Media

Magnetic thin films can be fabricated by various techniques, **SPUTTERED THIN-FILM MEDIA**

but three major ones have been used commercially by the
thin-film media industry.
Electroplating played an important early role and was the
first technique to deposit thin films of magnetic material,
such as Co or CoNi, on with buffers to maintain the solution pH. This technique is create a plasma, containing electrons and ions— Ar^+ in the no longer considered suitable however for high-density me. case of argon, the most commonly used iner no longer considered suitable, however, for high-density me-
dia for reasons of film density, nonuniformity, and defects. are accelerated towards the target (cathode) where they eject

first used in flexible media (29) and later used in rigid-disk the geometry of the system, can travel to be deposited on the system of diode sputtering. media manufacturing. In this process, materials such as C₀, substrate. This is a description of diode sputtering.
FeCo, or FeCoCr allows are inductively melted and evano-
In magnetron sputtering, the plasma is additional film uniformity. The evaporated material is deposited onto

and yields highly compact, dense film that is well suited to Electrical power can be supplied as RF, lower-frequency
high-areal-density recording. Importantly, sputtered metal ac, or dc power, but dc power provides the hig alloy deposits can closely copy the chemical composition of the rate, is more stable, and is best suited to manufacturing.

The second technique was thermal evaporation, which was atoms of the target material, some of which, depending on st used in flexible media (29) and later used in rigid-disk the geometry of the system, can travel to be dep

FeCo, or FeCoCr alloys are inductively melted and evapo-
rated on to a substrate that is constantly moving to ensure centrated above the target by an enclosing magnetic field flux rated on to a substrate that is constantly moving to ensure centrated above the target by an enclosing magnetic field flux
film uniformity. The evaporated material is deposited onto located at the sputtering sources. The m substrates at an angle away from normal incidence. This was posed in such a way that the electrons are trapped in a region reported to yield advantages such as higher in-plane anisot- near the target surface, causing more intense ionization ropy, and therefore higher coercivity and better hysteresis there. In standard sources, most of the sputtering occurs in loop squareness, all of which are needed in longitudinal re- an annular region around the center, as is shown in Fig. 4. cording (30). This oblique deposition scheme was also helpful The fierce ion bombardment does cause localized heating of in that it allowed two sides of rigid disks to be deposited si- the target, and this heating can cause some target materials multaneously. Figure 3 illustrates the oblique evaporation to shatter if very large thermal gradients are allowed to deprocess of making a rigid media disk. The evaporation meth- velop and the target material cannot dissipate the heat fast ods have been surpassed by sputtering. enough. Sputtering targets and cathode systems are therefore Sputtering, the third technique, is now the most important cooled by flowing water to assist in dissipating the heat.

ac, or dc power, but dc power provides the highest sputtering

Place of Sputtering in the Disk-Manufacturing Process. Figure growth are minimal. The confinement of the electrons 5(a) shows a flow chart of the process for making disks and through the action of the Lorentz force is i

can be quite simple and operation only requires application of an electric field between the cathode and anode. During diode sputtering, a plasma of positive inert-gas ions and electrons is generated, but the plasma is not closely confined. Many electrons therefore can bombard the substrate, which increases the substrate temperature in an uncontrolled manner and so affects film growth. It was found that the sputtering efficiency for this technique was low and that the film mechanical properties could not be kept within a narrow range. The diode technique was therefore quickly abandoned and was replaced for magnetic media by magnetron sputtering.

In magnetron sputtering, the cathode target design accommodates a magnet behind the target whose external field encloses the surface of the sputtering target. Under the influ-Figure 4. Schematic diagram of sputtering from a circular target. ence of both the applied electric and magnetic fields, plasma
electrons are strongly confined and so both the electron heating of the substrate and the consequent interference in film

problem is commonly observed in dc sputtering of carbon tar-
surfaces and dip lubrication. The disks are then subjected to problem is commonly observed in dc sputtering of carbon tarhead glide (flying) and certification tests. gets but can easily be overcome by using RF magnetron sputtering. By preventing the accumulation of charge on the tar-**Types of Sputtering.** The main sputtering categories are di- get, a radio-frequency oscillating electric field eliminates ode sputtering, dc (constant-field) magnetron sputtering, rf micro-arcs and so minimizes the introduction of defects in the (radio frequency) magnetron sputtering, and ac (alternating- disk surface. However, RF magnetron sputtering is not as field) magnetron sputtering. Straightforward as dc sputtering in its operation, because it Diode-sputtering systems are undemanding in design and is less stable and because it demands careful matching of the construction and were the first to be used because the cathode power source to the dynamic load that the sputtering system

Figure 5. (a) The disk-manufacturing sequence. (b) A configuration of a pass-by type of sputter system (ULVAC sputtering system). [Fig. 5(b) courtesy of ULVAC.]

Figure 6. Schematic arrangement of a magnetron sputtering system.

nique. To minimize instability problems and to permit use of figuration that is going to be used. There is no absolute recipe less conductive targets without micro-arcing, the lower-fre- for making a universally good magnetic recording medium; in quency $(< 1$ kHz) ac magnetron sputtering can be used with industrial production, certain process parameters cannot be improved results. However, most disk makers currently use adjusted for optimal media performance because of condc magnetron sputtering because it is simple and reliable. straints on production throughput and practicality. For exam-

sputtering process has a great impact on thin-film mechanical not been adopted commercially because of its limited properties, magnetic properties, and recording performance. throughput. For magnetic recording media, the sputtering process is as important as correct selection of the magnetic alloy composi- **Sputtering System Configurations.** An additional aspect of

ergy of adatoms that finally controls the film growth and film targets that can readily be exchanged. In these systems, it is properties. It has been demonstrated that altering the mobility of the adatoms causes large changes in the mechanical and magnetic properties and in the morphology of the magnetic film. Figure 7 is the classic diagram that illustrates how the sputtering process affects film growth, which therefore alters the film properties (31,32). Films sputtered onto a substrate at high temperature, high substrate bias voltage, low argon pressure, and high sputtering power tend to be fully dense and to have few grain boundaries. The grain size of the films sputter deposited under these conditions therefore tends to be relatively large and the films have a well-defined grain morphology. On the other hand, films sputter deposited under conditions of lower substrate temperature, no bias, higher working pressure, or lower sputtering power tend to be porous, with a smaller grain size and wavy film surface morphology. Gao, Malmhall, and Chen studied and reported on the correlation between sputtering process conditions with film mechanical properties (32,91).

To make media that have good magnetic properties and good recording performance, the preferred sputtering parameters are high substrate temperature T_{sub} (for NiP/A1 substrate media, this means above $T_{sub} = 250^{\circ}$ C), about a 250 V substrate bias, low pressure, and relatively high sputtering power. Of course, making a medium with specified magnetic **Figure 7.** Schematic illustration of the effects of bias voltage, sputter properties requires a combination of these sputter-deposition chamber pressure, and subst parameters. How to select a suitable combination depends on ogy and grain structure.

presents. Few disk makers have therefore used this tech- the actual sputtering system, alloy selection, and media conple, low-mobility sputtering can usually result in a medium **Effects of Sputtering Process Control on Media Properties.** The with a better signal-to-noise ratio (SNR), but the process has

tion and of the underlayer materials. Many parameters and sputtering systems that is important to making good refactors affect the sputtering process. For example, changes in cording media is the configuration of the sputtering systems the sputtering power, the sputtering working pressure, the as *static* or *pass-by.* In pass-by systems, the substrates are substrate temperature, and the substrate bias voltage all act conveyed past the sputtering targets; in static systems the to change the mobility of deposited adatoms. substrates are stationary in front of target during film deposi-Although the sputtering process is complex, it is the en- tion. The static types of systems are usually smaller and have

chamber pressure, and substrate temperature on thin film morphol-

also easier to develop and to control the sputtering process. Pass-by sputtering systems usually have the advantage in or both should occur. mass production if the sputtering yields can be properly Coercivity in thin-film media is predominantly controlled

good magnetic property uniformity around the circumferen- magnetic interaction between grains, and by the extrinsic astial direction but less so in the radial direction. Radial varia- pects of the microstructure of the magnetic media that influtions can, however, be minimized by optimizing both the mag- ence the difficulty of domain-wall motion and of nucleating netic flux distribution in front of the target surface and also reverse domains. Both intrinsic anisotropy and media prothe combination of sputtering power and duration. On the cessing must be optimized to create media with high loop other hand, pass-by sputter systems usually yield disks with squareness and high coercivity. better magnetic property profiles in the radial direction. Studies have shown that pass-by sputtering systems tend to pro- **Anisotropy and Its Origin.** A magnetic recording medium exvide disks with poorer modulation in the circumferential di- hibits a high coercivity and a high hysteresis loop squareness rection (33,34) but that this problem can be minimized by because of the anisotropy and the interactions among the depositing an appropriate seed layer underneath the under- grains in the film. The total, or effective, anisotropy of a melayer and the magnetic layer (35–37). dium is the sum, principally, of three parts: crystalline anisot-

chambers than those of static sputtering systems; sufficiently ing due to the film stress created during the sputtering good vacuum is therefore harder to attain and maintain. process. This total anisotropy is therefore Studies have shown that vacuum integrity is also important to making high-density recording media disks of high quality and that improved vacuum correlates strongly with higher coercivity in the disk (38,39). Therefore it is common that Here, K_u is the magnetic anisotropy constant, which is an in-

Magnetic Properties of Thin Films. Magnetic properties that characterize media are most importantly the intrinsic anisotcharacterize media are most importantly the intrinsic anisot-
ropy, the coercivity H_c , the saturation magnetization, the contribute up to one-quarter of the total medium coerciv-
squareness S, and the coercivity squaren

relationship with the recording readback amplitude. As the
media density is increased, the magnetic transition length pa-
rameter a must become shorter. According to the Williams-
rameter a must become shorter. According

sition, either H_c should be increased or M_c should be reduced.

maintained. by the magnetocrystalline anisotropy of the target materials, Disks sputtered in static sputter systems usually have by processing that affects the film microstructure and the

Pass-by sputtering systems usually tend to have larger ropy, shape anisotropy, and elastic anisotropy, the latter be-

$$
K_{\text{total}} = K_u + K_{\text{shape}} + K_{\text{elastic}} \tag{12}
$$

magnetic alloys with higher anisotropy have to be used in trinsic parameter and is determined for each crystalline pass-by systems to achieve the same media coercivity as is phase by its composition and structure. K_{shape} and K_{elastic} are obtained in static sputtering systems with alloys of lower an- extrinsic parameters and so their values are process depenisotropy. Constantly improving and optimizing the vacuum dent. K_{shape} includes the effect of the geometry of the thin film performance of sputtering system is an important and essen- and the shape of the grains and depends on the sputtering tial task for system makers. process and on the surface morphology of the substrate. K_{elastic} includes strain and stress effects but contributes sig-**Thin-Film Media Magnetics** nificantly if the medium possesses a nonzero magnetostriction (magnetostriction constant $\lambda \neq 0$). In the CoCrTa alloy system, $K_{elastic} = \frac{3}{2}\lambda\sigma$, where σ is the mechanical film stress, and

squareness S, and the coercivity squareness S^* [or the switch-
ing field distribution (SFD)]. Since the film coercivity encoun-
tered by a recording head is actually the remanent coercivity
distance texture of the disk The product $M_r \delta$ of remanent magnetization M_r and me-
dium physical thickness δ is often used because of its direct
between the radial and circumferential directions (38.42), and

rameter a must become shorter. According to the Williams-
Comstock model [Eq. (8)], to reduce a and so shorten the tran-
the underlayer—parallel to the (002) plane of the underlayer
parallel to the (002) plane of the unde in the case of a body-centered-cubic underlayer structure. In this case, therefore, the grain *c* axes lying along the texture groove lines do not tilt out of the film plane, whereas *c* axes perpendicular to the texture groove lines may be tilted out of the film plane.

> Statistically, a predominant effect of *c*-axis alignment along texture grooves is observed. This last hypothesis is convincing and is confirmed by experiments with and without substrate heating (39) . On the other hand, K_{elastic} may not depend only on one mechanism; two or three mechanisms may actually combine to change the total anisotropy K_{total} .

Magnetostatic and Exchange Interactions and the Loop Figure 8. Hysteresis loop of a thin-film disk. **Squareness.** The origins of hysteresis squareness behavior

principally explored exchange energy aspects. The total en- movement of domain walls. ergy density *E*^t describing the magnetization therefore is Understanding the mechanism of magnetization reversal

$$
E_{\rm t} = E_{\rm a} + E_{\rm m} + E_{\rm e} \tag{13}
$$

exchange energy densities, respectively. The hysteresis noise but the second mode usually leads to high media noise. squareness depends on their magnitudes and on their relative Media noise is a key limiting factor that we discuss in the contributions to E_t . later sections.

For a medium that has high magnetostatic grain interactions among grains, the hysteresis loop is square but has **Magnetic Alloy Selection.** Magnetic alloy selection predomi-
lower H_c. When the exchange interaction is taken into ac-
nantly depends on the bulk magnetic proper lower *H*_c. When the exchange interaction is taken into ac-
count, the hysteresis loop of the medium obtained by com-
the film coercivity *H*_c required to satisfy hard drive specificacount, the hysteresis loop of the medium obtained by com-
puter modeling also showed higher loop squareness and tions based on recording models such as that of Williams and puter modeling also showed higher loop squareness and tions based on recording models such as that of Williams and
smaller coercivity. Chen and Yamashita obtained experimen- Comstock. The next most important is the media s smaller coercivity. Chen and Yamashita obtained experimen-
tal confirmation of this result. Figure 9 shows the media mor-
noise ratio performance attainable with alloys of suitable H_{α} . phology and the hysteresis loops of three film media whose This selection criterion has become significantly more imporgrains have different magnetostatic and exchange interac- tant as the media areal density has increased. tions (46). Early magnetic inductive media required only low coerciv-

were explored theoretically and experimentally by Hughes, and in the third, the grains are not strongly exchange coupled Bertram, and Chen. Hughes (44) considered magnetostatic but are coupled magnetostatically, over a longer range, in energy and anisotropic energy and Zhu and Bertram (45) magnetic domains in which magnetic reversal occurs by

is of great importance in making high-performance media, because the mechanism of the magnetization reversal directly relates to the media noise and the media signal-to-noise ratio. where E_a , E_m , and E_e are the anisotropic, magnetostatic, and For example, the first reversal mode results in very low media

noise ratio performance attainable with alloys of suitable H_c .

ity (less than 2000 Oe) to deliver a high signal, and so the **Magnetization Reversal.** Magnetic reversal in thin-film me- bulk magnetic properties were of greatest concern. Most of dia can be classed into three different models: In the first, the the alloys used were then CoCrTa, CoNiCr, CoCr*X* (where *X* grains are completely separate and reverse their magnetiza- represents a different element) or something close to these tion independently; in the second, the grains are strongly ex- ternary systems. As the required coercivity is increased, howchange coupled and are grouped closely together as grain ever, alloys with higher magnetocrystalline anisotropy must clusters, which reverse their magnetization cluster by cluster; be considered. For this purpose, Pt-containing alloys have

Figure 9. Morphology and hysteresis loops of films with different intergranular interactions.

Figure 10. Process effects on H_c and the media signal-to-noise ratio for CoCrPtTa and CoCrTa media on Cr underlayers: (a) underlayer thickness, (b) bias effect, (c) substrate temperature, and (d) chamber pressure. Curves 1 and 2 refer to differing media compositions within the labeled alloy system.

been the most popular choice, although other alloy systems the designed values. In manufacturing, for a specified maghave been demonstrated to give higher film coercivity (47). netic property specification, the coercivity H_c can often be con-Currently popular alloys with high crystalline anisotropy are trolled by the substrate temperature and the underlayer CoCrPtTa, CoCrPt, CoCrPtB, or CoCrPtTa*X* where *X* can be thickness, which in turn are set effectively by the heater Ni, B, Si, Zr, or Hf. Many studies have shown advantages in power and the underlayer sputtering powers, respectively. recording performance resulting from the addition of a fifth The product of remanent magnetization M_r and magnetic element X to CoCrPtTa. The performance enhancement includes improvements in media signal-to-noise ratio, and/or and the squareness of the hysteresis loop. Depositing films overwrite and PW $_{50}$ improvements (48,49). However, the under conditions of higher adatom mobility tends to form

Process Control. The magnetic properties of the media films establish a desirably small switching-field distribution closely depend on the film-making process. When the media (SFD), or equivalently large S^* (approximately $S^* = 1$ – configuration is defined—that is, when the underlayer, seed SFD), the coercivity squareness, which is layer (which is sometimes used) and magnetic alloys are de- narrowness of the range of applied magnetic fields required fined—variations in the process of fabricating the media still to flip the magnetic moments in the film. Figure 11 shows exhibit pronounced effects on the magnetic properties of the the effect of process parameters on *S** of a CoCrPtTa film medium. The coercivity depends strongly on the sub- alloy system. strate temperature, the underlayer thickness, and the substrate bias, and sometimes also on the sputtering working **Thin-Film Media Microstructures** pressure. However, sputtering under higher power density minimizes the pressure effect on film coercivity. Figure 10 Cobalt-based alloys with hexagonal close packed (hcp) strucshows the effects of these process parameters on the film coer- ture have been developed for use as the current longitudinal civity of a CoCrPtTa medium. recording media. However, to confer on them the required

with magnetic properties lying within a narrow range about underlayer with a specific microstructure and crystallo-

layer physical thickness δ is controlled by the layer thickness physics behind these gains is still under active discussion. magnetic films with the *c* axes oriented in the film plane, which increases loop squareness and, therefore, increases **Correlation of Magnetic Properties with Sputtering Process and** the *M*^r of the medium. These deposition conditions also help SFD), the coercivity squareness, which is a measure of the

Process control is an important aspect in fabricating media magnetic properties in the read–write recording process, an

the Cr underlayer thickness on CoCrTaPt media. (b) Effect of bias on

graphic orientation is needed. Three decades ago, Lazzari, orientation relationships. Melnick, and Randet (50) found that a Cr underlayer in-

It has been accepted for the last decade that the mechanism behind this coercivity increase is lattice-match-induced epitaxial growth of the magnetic film in a suitable crystallographic orientation. In a polycrystalline film with the easy magnetic axis of each grain oriented randomly, the magnetic anisotropy averages to zero and the film is isotropic. The only significant coercivity-enhancing mechanism then available is the shape anisotropy from the film itself and so it is difficult to obtain high coercivity and good hysteresis squareness. However, if an underlayer such as Cr, or a Cr alloy with B2 crystal structure in an appropriate orientation is deposited prior to the cobalt-based alloy, the crystalline orientation of Co- or Co-based alloys can preferentially be altered to enhance both the film coercivity and the hysteresis squareness. It is generally accepted that this underlayer effect is essential to ensuring alignment of the *c* axis of an hcp cobalt alloy structure in the film plane and so is critical in longitudinal recording.

Magnetic Layer Microstructure. To make a medium with square-hysteresis characteristic, which is highly desirable for **Figure 12.** The crystal structure relationship of Cr and Co for better longitudinal recording performance, an appropriate $Co(10.\overline{1})$ crystal planes parallel to Cr(110) planes.

magnetic microstructure is essential. The squareness of the hysteresis loop originates both from the intergranular interactions and from the distribution of easy *c* axes. Calculation shows that a three-dimensionally random distribution of the easy axes of a magnetic constituent, without counting the interactions among the grains, has a remanent M_r that is only half of the saturation magnetization M_s and that a twodimensional random easy-axis distribution has M_r equal to 0.62*M*^s (51). Highly compact, sputtered grain structures with little grain separation usually result in strong magnetostatic interactions and so assist in achieving higher loop squareness. To obtain *c*-axis orientation in the film plane, the (11.0) or (10.0) planes of an hcp structure have to be grown parallel to the film plane. This can be done through control of the sputtering process but can most easily be achieved through epitaxial grain growth on top of an underlayer with the appropriate atomic structure, as discussed in the next section.

Crystalline Orientations of the Magnetic Layer and Underlayers. The most commonly used underlayer materials in current magnetic recording media are Cr, Cr-based alloys, or alloys with B2 crystal structure and similar atomic lattice constants (52). This structure is depicted in Fig. 12, which also lists atomic lattice constants. As we discussed in the preceding section, a specific orientation is needed for the desirable form of Co-based alloy film growth. Many studies have shown that having the (002) lattice orientation of the suitable B2 underlayer structure parallel to the film growth surface will induce epitaxial growth of an hcp Co alloy magnetic layer because of the close lattice match between the (11.0) plane of the Co alloys and the (002) plane of the CrX $(X = V,$ **Figure 11.** Process effects on coercivity squareness S^* . (a) Effect of \mod{M} , . . .) underlayer (50). This (11.0) orientation corresponds the Crunderlayer thickness on CoCrTaPt media (b) Effect of hiss on \mod{C} cthe CoCrTa media on Cr underlayers. Curves 1 and 2 in each case has also shown that *c*-axis alignment or in-plane texture, in refer to differing compositions within the same alloy systems. the magnetic layer could be promoted by epitaxial film growth on Cr (112) and (110) orientations of the surface planes of the underlayer (53). Figure 13 shows the atomic structure and

creased the in-plane coercivity of Co-based alloys. **Film Morphology, Grain Size, and Grain-Size Distribution.** For

Figure 13. The crystal structures and relationship between Cr and Co, relevant to a $Co(110)||Cr(002)$ texture [i.e., with the $Co(110)$ crystal planes parallel to the Cr(002) planes].

the correct atomic structure and crystalline orientation, it is also necessary to have uniform film morphology, small grain size, and narrow grain-size distribution. Studies have shown that, as the recording media layer is made thinner, the film growth technique becomes increasingly critical (54–57). Achieving two-dimensional film growth is preferable to threedimensional growth—a surface and interfacial energy issue. A suitable substrate sublayer—for example, a NiP plated layer—can help establish a two-dimensional growth mode that improves the mechanical integrity of the subsequent layers. When the surface energy of a depositing layer has smaller surface energy than the existing surface material, the depositing adatoms tend to enlarge the existing surface layers by diffusing until they can be accommodated on the lower side of steps at the boundaries of the layers. This two-dimensional mode of growth therefore tends to form a continuous film by extension of the existing topmost layer in the plane of the **Figure 14.** Two types of epitaxial growth of a Co-alloy magnetic surface. On the other hand, when the material of the depos- layer on a Cr underlayer. iting layer has a higher surface energy than the existing surface material, the depositing layer tends to grow in three dimensions by the formation of islands. For high-recording-
density media the layer-by-layer two-dimensional film morphology that we discussed earlier. When the grains are density media, the layer-by-layer, two-dimensional film morphology that we discussed earlier. When the grains are
growth is particularly desirable since the magnetic film thick-
ness must be very small and the mechanical i ness must be very small and the mechanical integrity of the form morphology that can is otherwise head to maintain. Figure 14 illustrates the sequent processing. film is otherwise hard to maintain. Figure 14 illustrates the

The magnetic layer grain size is another key parameter that affects the film magnetic properties and recording performance in several ways. Figure 15 shows the dependence of H_c on grain size—behavior that is observed by many researchers (58–61). The coercivity initially increases with increasing grain size and then drops for grain sizes larger than 40 nm. The recording performance is also closely related to the grain size and to the grain size distribution. The smaller grain sizes and narrower grain-size distributions result in lower media noise and higher media signal-to-noise ratio, since the media noise originates in zigzag domain-edge irregularities, whose dimensions are correlated with the grain sizes. Therefore, controlling the grain size and minimizing the width of the grain-size distribution are important goals for media makers. Approaches to these goals include (1) selection $\begin{array}{cccc} 0 & 10 & 20 & 30 & 40 & 50 \\ 0 & 0 & 0 & 30 & 40 & 50 \end{array}$ of materials with different surface energies, (2) selection of the underlayer or seed layer, and (3) optimization of the film **Figure 15.** Grain-size effect on coercivity H_c .

two types of film growth, which result in quite different re-

cording performance (54).

The magnetic layer grain size is another key parameter the magnetic film grain size and switching volume have im-

portant effects on both the media performance and the ther- good magnetic recording media. As discussed in the sections mal stability in high-density recording media (62–64). For entitled ''Thin-Film Media Magnetics'' and ''Thin-Film Media low noise, as discussed previously, a small grain size is pre- Microstructures," the film microstructure is strongly depenferred. However, for sufficient thermal stability of the written dent on having the sputtering process yield a magnetic layer information, the quantity $K_u V/(k_B T)$ —the ratio of the energy with its *c* axes in-plane and it is clear that this requires prefassociated with the magnetic anisotropy of the magnetic erably an underlayer of B2 structure with [200] texture. In switching volume to the unit of thermal energy—must be suf- practice, this [200] orientation requires sputtering conditions ficiently large (65). (In this ratio, K_u , k_B , T , and V are the that provide high adatom mobility. These conditions involve magnetic anisotropy, Boltzmann's constant, the temperature, (1) high sputtering power, (2) and the magnetic switching volume, respectively.) Thus, one high substrate bias, and (4) low sputtering pressure. The would expect that there might be an optimal magnetic switch- [200] crystalline orientation has been grown on glass subing volume and so grain size, although these may not be iden- strates by varying the substrate temperature (69). Figure 16 tical quantities. illustrates how [200] texturing can be achieved by varying the

process and the correlation between the reversal process and conditions are critical for the underlayer but less so for the media noise, it is instructive to investigate the switching (ac- subsequent magnetic layer. It is observed that, even although tivation) volumes and the physical grain sizes. It is known higher-energy adatoms are required for formation of [11.0] or that these do not match for most materials, but the relation- [10.0] orientation films of hcp Co-based alloys, once the [200] ship is not fully understood at present. It is expected, how- structure of underlayer is laid down, the epitaxial influence ever, that the medium noise should be related to the volume on subsequent growth is stronger than the influence of the of the grains and/or the switching volume, since both quanti- process conditions. ties are relevant to the possible spatial resolution for re-

Researchers have demonstrated that magnetization rever-
sals do not imply switching volumes that are always identical the morphology of deposited media films, and the film-growthsals do not imply switching volumes that are always identical the morphology of deposited media films, and the film-growth-
with the physical grain size (66). In the simplest case, switch-
process parameters are demonstrat ing by homogeneous rotation of the magnetization, one would media. High substrate temperature, high substrate bias, high expect the physical grain and the switching volumes to coin-
nower-density sputtering, and low workin cide. The observed mismatch between physical grain and tering result in a film with well-defined grain morphology and
switching volumes has been known (67) and attributed to in-with a strong tendency for the c axes to be a switching volumes has been known (67) and attributed to in-
homogeneous magnetization reversals. Typically, for rather plane As an example Fig. 17 shows the transmission elechomogeneous magnetization reversals. Typically, for rather plane. As an example, Fig. 17 shows the transmission elec-
large particles, as occur in magnetic tape media, switching tron microscope (TEM) images of films for a large particles, as occur in magnetic tape media, switching tron microscope (TEM) images of films for a range of sput-
volumes are reported to be smaller than the particle volumes. tering pressures and Table 2 gives the co volumes are reported to be smaller than the particle volumes. tering pressures and Table 2 gives the corresponding atomic
Physically, this may be interpreted by assuming that the structure change and the ratio of the c axi Physically, this may be interpreted by assuming that the structure change and the ratio of the *c* axis in the plane of thermal energy $k_B T$ can cause a change in the magnetization the film to that out of the plane of the thermal energy $k_B T$ can cause a change in the magnetization the film to that out of the plane of the film. Since this mor-
in only a certain fraction of the particle volume (i.e., the phology, the lattice structure, and in only a certain fraction of the particle volume (i.e., the phology, the lattice structure, and the orientation variations switching volume) in order to reverse the magnetization in are all results of sputtered adatom mob that region of the particle. An example for such an inhomoge- process parameters that similarly affect the adatom mobility neous thermally assisted magnetization-reversal process was can be expected to change the film morphology and lattice theoretically analyzed in Ref. 68. Experimental measure- structure in a similar way. ments imply that the magnetization-reversal process in ''large'' single-domain grains is inhomogeneous—most likely **Thin-Film Media Structures and Configurations** initiated at defect locations. On the other hand, when grains are too small to support a domain structure, they will switch Although thin-film media structures have evolved into several
entirely Thus films with larger single-domain grains are ex-
different configurations, illustrated entirely. Thus films with larger single-domain grains are ex-

interaction. Since magnetic interactions between grains must is deposited, followed by the magnetic layer(s), and finally a
have an influence on the magnetization-reversal process by protective overcoat layer, typically a have an influence on the magnetization-reversal process, by protective overcoat layer, typically a form of carbon. The affecting the external field at each nearby location they will whole sputtering deposition process is c affecting the external field at each nearby location they will whole sputtering external process is carried out with $\frac{1}{2}$ affect the switching volume as well. Experimentally it is vacuum chamber. affect the switching volume as well. Experimentally, it is found, however, that decreasing the grain size does not change the switching volume significantly. On the other hand, **Conventional Magnetic Media.** Conventional media strucgrain size controls the nature of the interactions in the mag- tures always have an underlayer, a magnetic layer, and an netic media. One may speculate that making the grain and overcoat. Commonly, the underlayers are Cr, Cr*X* alloys with switching volume the same will result in a good design of re- *X* representing elements that primarily include V, Ti, Mo, Hf, cording medium. Zr, and W in concentrations between 0 at.% and 30 at.%. The

selections of a suitable magnetic alloy and a suitable combina- second to inhibit development of larger underlain grains. The tion of underlayer and magnetic layer are essential. However, magnetic layer is now usually a quaternary CoCr*XY* alloy in the film-deposition process is equally important for making which *X* and *Y* are Ta, Ni, Pt, Nb, and other elements. Ter-

 (1) high sputtering power, (2) high substrate temperature, (3) For a better understanding of the magnetization reversal underlayer thickness and substrate temperature. The process

cordings on these films. **Correlation of Thin-Film Microstructure with the Film Fabrica**process parameters are demonstrated in Fig. 17 for CoCrPtTa power-density sputtering, and low working-gas pressure sputare all results of sputtered adatom mobility, other sputtering

pected to be noisy.
An additional factor that must be considered is magnetic same. Basically, an underlayer, typically of Cr or Cr alloy. An additional factor that must be considered is magnetic same. Basically, an underlayer, typically of Cr or Cr alloy,
eraction Since magnetic interactions between grains must is deposited, followed by the magnetic layer(s)

rationale for the *X*-element addition is first to alter the Cr **Process Control of Thin-Film Microstructure.** It is clear that lattice spacing while retaining the bcc crystal structure and

Figure 16. Influence of changes in Cr underlayer thickness and substrate temperature on filmgrowth texture observable through x-ray diffraction patterns, whose peaks reveal the major crystal planes parallel with the disk surface.

ties as high as 4 kOe in thin film media. This dependence of alloys to build one working magnetic layer (80). coercivity on Pt concentration is quantified in Fig. 19. Carbon films have been used successfully as protective layers since **Sandwich-Layered Magnetic Media.** A nonmagnetic spacer the start of thin film media manufacturing. However, it has layer sandwiched between two magnetic layers can reduce the later been demonstrated that both hydrogenated and nitro- effects of intergranular exchange coupling and of demagnetizgenated carbon films are even better than pure carbon films ing fields. Once the sandwich-layered construction was dem- (70,71). Both CN*^x* and CH*^y* are currently in use by disk onstrated to confer lower media noise and higher media SNR makers. (81–84), sandwich-configuration media were produced at the

found that a double underlayer could result in better mag- However, producing media with dramatically increased arnetic and recording performance for some alloys and certain underlayer materials (72–75). The first underlayer serves two quired a reduced magnetic film thickness. This is incompatipurposes: It acts as a seed layer by initiating growth of ble with inserting a nonmagnetic spacer between two smaller grains and by establishing a suitable epitaxial rela- magnetic layers, since the film coercivity then suffers a severe tionship in the deposition of the second underlayer. The sec- drop and the distance between the outermost surfaces of the ond underlayer therefore grows both with the correct crystal- magnetic layers is increased. The coercivity decrease is grainline orientation and with a smaller grain size. This double underlayer approach has frequently been used for media, par- the grain sizes at which the grains are no longer ferromagticularly in the pass-by type of sputtering system. The two netic—the superparamagnetic size limit. Therefore, sandwich underlayer materials need not be the same, but may be different, depending on the specific process, magnetic property re- unless a new alloy with yet higher crystalline anisotropy is quirement, and substrates used in the media design found. (57,76,77).

Engineering of the working magnetic layer structures can The concept was to enclose a larger magnetic transition flux also modify and improve the recording performance. The film and so to boost the signal that had not been used in any comcoercivity can be increased substantially and the medium mercial product. Since high-saturation magnetization materi-

nary alloys without Pt were used in the early days for thin- signal-to-noise ratio can be enhanced significantly by several film media with relatively low H_c ($H_c < 2.5$ kOe) but have process modifications: (1) using a flash magnetic layer before been replaced by quaternary Pt-containing alloys for media depositing the working magnetic layer (78,79), (2) depositing requiring higher *H_c*. The addition of Pt linearly increases the the same magnetic materials under successively different coercivity at low concentrations and has resulted in coercivi- sputtering condition (49), or (3) using two different magnetic

time when the media still had relatively high M_r δ . These **Seed-Layered or Double-Underlayered Media.** It has been layer-spacing effects are illustrated in Fig. 20.

> eal density necessitated lower $M_r \delta$ and higher H_c and so resize related and, in fact, at low enough $M_r\delta$ one could reach media are only useful in applications for higher- $M_r \delta$ media.

Keeper-Layered Magnetic Media. Keeper-layered media **Flash Magnetic Layer and Double-Magnetic-Layer Media.** were another early invention in the field of inductive media.

100 nm.

als must be used for the keeper layer, the results are higher demagnetizing fields and greater exchange coupling. Consequently, for keeper-layer media to be useful, the gain in signal amplitude must be balanced against the loss in media sig- If we can assume the slope of the hysteresis loop and the head nal-to-noise ratio, as Yen, Richter, and Coughlin have field gradient are constant, we can integrate this to obtain

Figure 18. The configuration of a thin-film medium.

demonstrated (88). Keeper-layer media therefore remain in the research laboratories but not in commercial production.

Recording Performance

Magnetic Transition Wavelength. During a magnetic head writing process, magnetic transitions are generated in the magnetic medium. The minimum repeat distance between the magnetic transitions is called the magnetic transition wavelength—the shorter the wavelength, the higher the number of magnetic transitions per unit distance. This transition length is illustrated in Fig. 21. Suppose the medium is dc erased (that is, erased with a constant applied field) and the magnetization is in the positive direction, with a value of M_r in the hysteresis loop. As the field of the head reverses and increases in magnitude, the magnetization reduces, following the hysteresis loop curve. At $H = -H_{c}$, the minor hysteresis loop illustrates that there will still be a small remanent moment left. So, to take the remanence to zero the reversal field must be increased in magnitude to slightly more than H_c —to a field that is commonly called the remanent coercivity H_{cr} .

Assume that a medium is being written by a head that moves in the *x* direction—the direction of the field gradient Figure 17. TEM micrographs showing the correlation between the $\frac{1}{2}$ in the gap in the recording head. Between media locations film microstructures and sputter gas pressure for a thin film system.
Sin microstructures estimated by

$$
\frac{dM}{dx} = \frac{dM}{dH} \frac{dH}{dx} \tag{14}
$$

Table 2. Easy-Axis Orientation of Magnetic Film versus Sputtering Pressure

Pressure (mTorr of Ar)			10	51	$\rm 20$	30	40	60
Angles $(\text{deg})^a$	90	85	70	– F	60	$20\,$	∸	У
$\operatorname{Interpretation}^b$	In	Jut	Jut	Эut	Out	Jut	Out	

^{*a*} Easy axis angles are measured with respect to the film plane normal. Completely in plane corresponds to 90[°] and fully perpendicular to the plane is 0°

b The interpretation of the angular orientation of the easy axes are in-plane (In), out-of-plane (Out), and perpendicular-to-plane (\perp).

$$
a = M_{\rm r} \bigg/ \frac{dM}{dH} \frac{dH}{dx} \tag{15}
$$

slope dM/dx) of the hysteresis loop of the medium. The mag-
netic transition is most popularly assumed to have the shape finite block of high permeability material with a flat face of an arctangent function (89,90), which leads for film media spaced a distance *d* above the medium and that the magnetic to flux distribution along vertical direction obeyed Poisson's

$$
a_{\min} = 2M_{\rm r}\delta/H_{\rm c} \tag{16}
$$

where δ is the magnetic medium thickness. Consequently, for the shorter magnetic transition lengths required for high lin-

Figure 21. Transition length of a thin-film medium.

ear recording density, thin media with low magnetization and high coercivity are preferred.

Readback Amplitude, Fundamental Signal of Thin-Film Media. Figure 19. Pt concentration effect on coercivity H_c of CoCrTaPt me- The presence of the magnetization distribution in the redia. Data sets 1 and 2 refer to differing underlayers. cording medium generates a magnetic field flux that extends over the surface of the medium. Based on Faraday's law, when a coil cuts through this flux, or, as in the case of an inductive readback head, a coil flies above a moving magnetic medium, a current will be generated in the coil. This current can be used as a signal and is proportional to the fluctuation of the magnetic flux changes over the surface of the media. This is essentially the readback signal. When this phenomenon was first studied, it was assumed that the magnetization which gives the importance of the squareness (through the had a longitudinal sinusoidal form. With the additional as-
slope dM/dx) of the hysteresis loop of the medium. The mag-
sumptions that the reproducing head consis finite block of high permeability material with a flat face equation, the flux per unit width Φ of the reproducing head $\frac{1}{\sqrt{2}}$ **was calculated to be**

$$
\Phi = \Phi_x = \int_{d+\delta/2}^{\infty} B_x dy
$$

= -[2\mu/(\mu+1)]2\pi\delta M \sin kx[(1-e^{-kd})/k\delta]e^{-kd} (17)

Figure 20. Effect of spacer layer thickness on $H_{\rm c}$, SNR, S^* , and $M_{\rm r}\delta$ in a double magnetic layer medium CoCrTa/Cr/ CoCrPtTa system.

with respect to the head, *t* is time, and *w* is the width of the from a sequence of transitions is a superposition of their indihead, the time derivative of the flux Φ is vidual amplitudes. In any sequence, two sequential transi-

$$
d\Phi/dt \propto 4\pi w v M[1 - \exp(-k\delta)] \exp(-kd) \cos \omega t \qquad (18)
$$

$$
V(t) = Nq \frac{d\Phi}{dt}
$$
 (19)

which is proportional to $\exp(-kd)$, the conclusions are (1) that there is a spacing loss that is dependent on *d* as **Pulse Width PW₅₀.** The recording signal pulse width is very

$$
20\log_{10}[10\exp(-kd)] = -54.6(d/\lambda) \, dB
$$

$$
(1 - e^{-kd}) = k\delta = 2\pi d/\lambda = \delta w/\iota
$$

Figure 22 shows Wallace's data of spacing loss and readback
signal dependence on frequency. He experimentally confirmed
the pulse width and derived the relation between PW₅₀
the behavior just described by inserting spac

proportional to the total intensity of the flux change. Thus and transition length.
any effort towards increasing the rotational speed of drive, the drive revolutions per minute, in the case of drives with magnetoresistive heads, is only for the purpose of increasing **Overwrite.** Overwrite is an important measure of the effecthe data rate and not for improving the readback signal am-
polity one frequency signal over a previously
plitude. The reader is referred to the excellent, detailed dis-
written pattern that is most probably of a different plitude. The reader is referred to the excellent, detailed discussion appropriate to the MR media, written by Bertram The practical way of assessing the overwrite characteristics is (89). $f(x) = f(x)$ first to write a pattern at frequency f_1 in the medium and

Using $x = vt$, where *v* is the linear velocity of the medium low linear densities of magnetization transitions. The output tions always have opposite signs. At a very high (spatial) frequency, the pulses are close together and tend to cancel each other, whereas at low frequency the pulses are completely Now if the head has a pickup coil with N turns and the effi-
ciency of the head is q , the voltage generated by the head
should be adhack process therefore exhibits nonlinearity at high fre-
should be quency. Only the ambiguously with the media $M_{\rm r}$ δ values. The high-frequency amplitude reveals information that includes the bulk magnetic property $M_{\rm r}\delta$ and the sharpness of pulses, pulse width Since the voltage is proportional to the flux time derivative, PW_{50} , which will be discussed in the next section.

much of interest in studies of magnetic recording media. The measure that is often used is PW_{50} —the pulse width at 50% of pulse amplitude—which describes the suitability of a meand (2) that there is a dependence of the readback signal on dium for achieving high linear recording density. The smaller
the medium thickness through the term the PW_{re} the greater the number of magnetic transitions th the PW_{50} , the greater the number of magnetic transitions that can occur both in the space domain and in the time domain. Therefore, the narrower the PW₅₀, the better the readback resolution will be.

ring head and a rotating magnetic disk during readback.
This discussion is given here for a medium read by an in-
 $\frac{du}{dx} = \frac{du}{dx} = \frac{du}{dx}$. The first dium thickness δ , and the transition length a that is given in-This discussion is given here for a medium read by an in-
ductive head (inductive media) but for a medium read by a
function of bood gap and fluing boight; their results are sen ductive head (inductive media) but for a medium read by a
magnetoresistive head (MR media), the starting point will be
different. For MR media the readback signal is not propor-
tional to the rate of the magnetic flux cha

To characterize the readback signal in media studies, aver- measure the readback signal $V_0(f)$, then to overwrite another age amplitudes are usually measured with high- and low-fre- pattern of frequency f_2 (e.g., $f_2 = 2f_1$ or $4f_1$) and measure the quency tracks—that is, tracks, respectively, with high and residual signal $V_{\text{Res}}(f_1)$ at frequency f_1 as well, and finally to

Figure 22. (a) Frequency effect on the read-back signal *V* (dB). (b) Dependence of the spacing loss (dB) on the ratio of the spacing *d* to recorded period of magnetization λ .

$$
\text{OW} = 20 \log \frac{V_0(f_1)}{V_{\text{Res}}(f_1)}
$$

For high-performance thin films, this parameter should be at
least over 30 dB.
In magnetic recording, the overwrite characteristics de-
pend on both media and head properties. For example, in
creasing the writing field or

properties. $H_{\text{eff}} = H_{\text{demag}} + H_{\text{head}}(x_0 + \Delta)$
Overwrite is largely controlled by coercivity and $M_r \delta$. Overwrite can indicate whether the coercivity of a medium is ex-
cessively high. When the coercivity of a medium is high, the
second set of magnetic transitions may not completely replace
the location x_0 enables the follow media, overwrite must be balanced against the need to have a short magnetic transition length and a small nonlinear transition shift (NLTS), which we discuss in the next section. This arises because a high-film coercivity is required for a
short magnetic transition length and small NLTS, but lower
coercivity is required for a good enough overwrite.

thickness, and head flying height. certainty in the transition location other than a geometric

Figure 25. Writing a transition in a moving medium.

Figure 23. Correlations between PW₅₀ and head gap *g*. of PW₅₀ to the transition separation is increased. When two transitions are written too closely together, the demagnetizing field from the previous transition affects the writing of the overwrite OW as the next transition. This results in a shift of the location of the transition and is called the nonlinear transition shift. This shift depends on the transitions that are already written. From the magnetic flux view point, the origin of NLTS can be

$$
H_{\text{eff}} = H_{\text{demag}} + H_{\text{head}}(x_0 + \Delta) > H_{\text{c}} \tag{20}
$$

$$
\Delta X = \frac{4M_r \delta (d + \delta/2)^3}{\pi Q H_c B^3} \tag{21}
$$

both $M_{\nu}\delta$ and d, is inversely proportional to medium coerciv-Nonlinear Transition Shift. At high recording density, mag-
netic transitions are nonlinearly distorted because the ratio
high-performance medium.

Media Noise and Media Signal-to-Noise Ratio. There has been concern that media noise will finally limit the attainable increases in areal recording density. Media noise is caused by the randomness and uncertainty of magnetic transitions and results from the characteristics of the magnetic constituents in the media. Any spatial variation and magnetic fluctuation will produce noise. As the packing fraction of grains in thin film media approaches unity and the related intergranular exchange coupling increases, the media noise increases at the higher recording densities. Figure 25 shows a medium with transitions produced by a writing head. As we discussed in the section entitled ''Magnetization Reversal,'' when all the $a + d$ grains reverse their magnetization independently under the **Figure 24.** Correlation between PW₅₀, transition length, medium influence of the externally applied field, there will be no un-

grain-size effect and there will be less magnetization fluctuation. Therefore, the magnetization transition will be sharp, leading to low media noise and high media signal-to-noise ratio. On the other hand, if the magnetization reversal occurs in grains clustered and coupled tightly together, the magnetization transition will not be sharp, because its location conforms to the boundaries of the clusters of grains. This magnetic structure generates a so-called irregular or zigzag transition wall and results in media noise. The origin of the clustered grain reversal behavior lies mostly in exchange coupling but also in magnetostatic interaction.

As progressively higher areal densities are sought, media noise becomes more and more a problem. To make a medium with lower noise, different techniques and approaches have been reported. (1) Physical grain separation: Magnetic grains
can be physically separated during the sputtering process by
creating microvoids in the grain boundaries. This mechanism
noise ratio obtained by media compositi of physical isolation, which cuts the exchange coupling, is an effective way of reducing media noise (91). However, this technique has not really been applied in production, because,

as discussed earlier for make a provas medium, lower sput-

are the track density is increased (for thigh areal density),

are read with the head slightly shif

jitter measurement algorithm described in Hewlett-Packard Application Note 358-3, the total peak jitter can be separated into write and read components. Under typical recording conditions, write jitter is known to be the dominant component of media noise. (Media noise also includes three variances associated with the readback waveform: peak jitter, PW_{50} fluctuations, and amplitude fluctuations.) By definition, write jitter is the standard deviation of the distribution of peak positions relative to their expected positions and is conveniently expressed in nanometers. If jitter measurements are performed at low recording density, in the absence of transition interference and NLTS, the peak write jitter is also the transition jitter. Transition jitter directly relates to the microstructure of the magnetic film.

Off-Track Capability. Unlike the other parameters we have discussed that characterize media performance, off-track capability (OTC), in units of length, refers to the performance change found when the readback head is positioned off the track center in a radial direction of the disk (94–96). **Figure 27.** Off-track capability curves for a group of media of dif-

on the magnetic disk, a certain positioning error is always positions.

Write Jitter. Peak jitter measurements are a valuable com-
plement to the popular technique of integrating the frequency
spectrum of media noise power. By using the standard peak (94).
 (94) .

When a head is positioned over a specified track written fering SNR as a consequence of differing underlayers and media com-

of head flying height (in multiples of 1μ in., i.e., 25.4 nm). in the industry.

at the head–disk interface. A very small separation between tion steps can improve the bonding. the head and the media can indeed lead to greater friction Studies have also shown that the molecular weight of the and increased wear (98). Therefore, interface and media lubricant has a strong effect on the tribological and increased wear (98). Therefore, interface and media head–media interface and thus involves controlling the dy- bility, low surface tension, and low vapor pressure. namics of the head and medium. The ultimate goal is to In addition to dip lubrication, vapor lubrication has been achieve contact recording with minimal friction and wear and investigated by disk makers for media intended for ultralow with minimal adhesion between head and disk. Figure 28 head flying height. If successful, vapor lubrication could reshows the relationship between the product of wear and stic- sult in still lower cost and better performance of magnetic tion as a function of recording head flying height. This behav- recording disk drives. ior occurs because at a higher head-media flying height both wear and stiction can be very low, but as the head–media **Substrate Texturing.** Applying a layer of lubricant does re-

reasons, glass, glass ceramic, and aluminum–boron-carbide texturing, (3) sputter texturing, and (4) intrinsic texturing. have been considered as alternative substrate materials. Glass and glass ceramic substrates have now also been used (1) In mechanical texturing, a tape coated with hard partiin commercial products. However, advances in the technology cles such as diamond or Al carbide is used to abrade

of the conventional substrates have repeatedly extended the possibilities for AlMg. The best AlMg substrates have been made with flatness better than 3 nm and with local substrate surface roughnesses of only about 0.2 nm. Therefore, conventional AlMg substrates are still preferred in the industry.

Overcoat and Lubricant. There are two aspects to disk tribology in addition to substrate texturing: the overcoat and the lubrication technologies. Disks require an overcoat after magnetic layer deposition for two important reasons—to protect the mechanical integrity of the magnetic layer and also to prevent or at least minimize corrosion of the magnetic layer. Carbon, or carbon modified by being hydrogenated or nitro-**Figure 28.** Head media products $[(\text{year}) \times (\text{stiction})]$ as a function genated, has been widely and effectively used as an overcoat

To allow the head to fly freely over the disk surface and to minimize wear resulting from contact between head and me- **Thin-Film Media Mechanics** dia, a lubricant must be applied over the protective carbon **Disk Tribology and the Head–Media Interface.** Magnetic re- layer. The lubricant is usually applied by dipping the disk cording is realized by the relative motion between a recording into a solution containing the lubricant or its precursor. The head and a recording medium. To obtain a high signal at a thickness of lubricant on the disk surfaces is controlled by the high linear density with a narrow track pitch, according to rate at which the disks are pulled out of the solution. A good the model of Williams and Comstock [Eq. (7)], the space be- bond between the lubricant and overcoat is needed to prevent tween the head and the medium should be as small as possi- the lubricant from being squeezed out from any contact beble. Therefore, the media surface needs to be made as flat and tween head and media and to prevent the lubricant flying off smooth as possible. However, smooth surfaces tend to lead to the disk surface during drive operation. Sometimes, double increased adhesion (stiction), friction, and thermal instability lubrication or baking the disk in an oven between two lubrica-

tribology is an important aspect of magnetic recording tech- (99). The class of lubricants that has been used extensively in nology, recognized as critical in the magnetic recording media disk industry are the perfluoropolyethers, including Fomblin industry. Resolution of friction and wear issues involves ap- ZDOL or Fomblin AM2001 lubricants. Perfluoropolyethers propriate selection of the substrate type and surfaces, the are long-chain fluorocarbon compounds, a desirable combinaovercoat film, the lubricants, and the environment of the tion of properties that include good thermal and chemical sta-

spacing is reduced both stiction and wear become large. The duce wear, but the meniscus force associated with the lubriproduct of the two tends to infinity as the flying height tends cant can cause serious stiction problems, sometimes resulting towards zero, namely for contact recording. in the recording head sticking to the surface of the media and causing drive failure. To solve this problem, technology has **Substrates.** Conventional thin-film substrates are made evolved for substrate ''texturing''—controlled introduction of from AlMg alloys containing about 5% Mg, since these have slight variations from surface flatness. (Note that, confusparticularly high mechanical hardness. The substrates are ingly, this texturing is not the same as the crystallographic stamp cut into circular plates and then electroplated with NiP idea of texture referred to in discussing underlayer and magfilm. This film further increases the surface hardness and also netic layer microstructure, in which similar crystallographic provides a base that can be highly polished. Aluminum sub- planes and directions in a polycrystalline material are more strates are widely used because they are good, easily made, or less closely aligned. However, texturing of a substrate surand low in cost, but concerns have been raised about whether face can indeed influence the crystallographic alignment, and they can be made flat enough to permit ultralow head-flying therefore the crystallographic texture, of subsequently deposheights and whether the hardness is high enough to with- ited layers.) Several different techniques are used for texturstand accidental head impacts without damage. For these ing disk substrates: (1) mechanical texturing, (2) laser bump

the substrate surface mechanically in the circumferential direction. This technique has been very effective
and the density of the bumps can be controlled to a
certain degree. This type of texturing is simple and of
and wi ential texture and Fig. 29(b) is an optimized circumfer- (4) Intrinsic substrate texturing applies to alternative

regions of the NiP layer and so to create bumps. Fig-

number density. The accuracy of creating bumps by this technique has allowed zone texturing of substrates—namely only laying bumps in the head landing or take-off zone to serve the tribological purposes and so leaving the data zone without texture. This is demonstrably a good strategy and is now widely used in the disk-making industry.

(3) Sputter texturing was probably one of the best low-cost methods. In this method, before the underlayer and magnetic layer are deposited, a sputter texturing layer is deposited using a film-growth technique that provides a rough film surface morphology. The subsequent underlayer and magnetic layer(s) then replicate the surface morphology of the texture layer and thus serve the required mechanical purpose.

Two types of materials have been used to create sputter textures, one by Mirzamaani and co-workers using lower melting point materials and the other by Gao and co-workers (101–103).

The first method relied on the concept of surface energy mismatch between the sputtered metal layer and the substrate. The relative surface energies play a central role in determining the film growth mode at thermodynamic equilibrium. If the deposited material has a larger surface energy than the substrate, it will tend to form three-dimensional structures, imparting a greater surface roughness that serves as substrate texturing. This is related to the wetting phenomenon that takes place between two materials that have different surface energies.

The second method relied on the concept of film stress and stress release. The substrate was held at high temperature during film deposition and then cooled at a controlled rate after the deposition, thus creating and then releasing the stress. The result of the stress release is to form hillocks or bumps. These **Figure 29.** Images of different types of disk substrate texture; de-
tails given in the text. these two technique. Figures 29(e) and 29(f) illustrate these two types of sputter-created bumps. The bump size, height,

ential texture with cross-hatch markings that demon- substrates, such as glass ceramic. The substrate strated to have greater tribological advantages. blanks are made with a mixture of amorphous and (2) Laser bump texturing was first demonstrated by Ran-

ian et al. (100) and is now widely used in the magnetic bedded in the amorphous matrix. If the amorphous jan et al. (100) and is now widely used in the magnetic bedded in the amorphous matrix. If the amorphous recording media industry. A relatively high-energy la-
phase is more easily removed, polishing leaves the recording media industry. A relatively high-energy la-
ser beam is used to recrystallize the polished surface harder crystallites protruding as surface bumps. On ser beam is used to recrystallize the polished surface harder crystallites protruding as surface bumps. On regions of the NiP layer and so to create bumps. Fig. the other hand, if the crystallites can be pulled from ures 29(c) and 29(d) contain images of two commonly the amorphous matrix, polishing may leave holes. Both used laser-created bump patterns. The bumps can be types of surface serve the necessary mechanical purquite precisely controlled in their size, heights, and pose and have been used to provide texturing in the

The future for magnetic recording media is strong—it is esti-
mated to be possible to develop media with a further order of
magnitude increase to 40 or even 100 Gbit/in.² in the areal
data recording density, based on de data recording density, based on development of currently **The Outlook for Magnetic Recording Media** known technologies and ideas. As yet no other data recording technology can compete in the combination of cost, capacity, The current development of magnetic recording media is now and speed. However, like anything else, magnetic recording highly advanced, but still offers considerable scope for in-
media must face limitations, both fundamental and techno-creased data storage per unit area, available logical. transfer rate. The closest competition is likely to come from

properties—high H_c and small $M_r \delta$. The coercivity of current
CoCrTaPt alloys is about 2500 Oe to 3500 Oe and the new
generation of media should have an H_c of 3500 Oe to 5000 Oe.
For future ultrahigh recording densit For still higher H_c , the new media will require both a high
intrinsic anisotropy and a microstructure optimized as dis-
cussed previously. As $M_r \delta$ is decreased, the read-back signal
discussed previously. As $M_r \delta$ is

cussed previously. As $M_i \delta$ is decreased, the read-back signal $\frac{1}{2}$ magnetic metals will need to have an improved micro-
decreases and increased head sensitivity becomes important. The magnetic media will need to ha

sities are more susceptible to thermally activated effects that alter the recorded magnetizations. Thermal activation not **BIBLIOGRAPHY** only causes the so-called superparamagnetic limit (104) but also leads to the transition decay of coercivity (105). The ratio 1. P. P. Zapponi, U.S. Patent No. 2,619,454, 1952.
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The areal density of longitudinal magnetic recording media $\frac{5}{5}$. M. Ishikawa et al., Film structure and magnetic properties of has increased at a compound rate of about 60% per year in CoNiCr/Cr sputtered thin film the last decade. Media are commercially available today with 1986. an areal density of 3 Gbit/in.² to 4 Gbit/in.²; 10 Gbit/in.² media are predicted to be available within a few years. Roughly alloys for rigid-disk applications, *IEEE Trans. Magn.,* **27**: speaking, from 1980 to 1990 more attention was paid to rais- 4739, 1991.

ties H_e and $M_e \delta$ and since 1990 more attention has been devoted to reducing media noise by improving micromagnetic THE FUTURE OF MAGNETIC RECORDING MEDIA size and distribution control are becoming important aspects
size and distribution control are becoming important aspects

creased data storage per unit area, available at high data near-field optical recording, which was recently announced **Magnetic Recording Media Limitations** (106,107). Near-field optical recording has been successfully It is worth discussing the approaches available for increasing
the areal density and trying to understand its limits. The key
limiting properties are: (1) media magnetic properties, partic-
ularly H_c and $M_r\delta$, (2) med ularly H_c and $M_r\delta$, (2) media noise, and (3) thermal instability.

In the sections entitled "Fundamentals of Magnetic Recording" and "Recording Performance," we have pointed out

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